

ABSTRACT OF THE DISCLOSURE

A load port transfer device. The device, for delivering a wafer carrier along an overhead conveying system, includes a load port, a path, and a robot. The path has vertical and horizontal components. The vertical component has a top portion connected to the horizontal component and disposed beside the overhead conveying system and a bottom portion extending from the load port. The robot is movably disposed on the path to transfer the wafer carrier between the load port and the overhead conveying system.